

ABSTRACT OF THE DISCLOSURE

An ion implantation apparatus. An ion implantation chamber has a movable work piece support holding one or more work pieces and a connecting housing between the ion implantation chamber and an accelerator thereof. A plurality of collectors with saw-toothed protrusions are mounted on the interior surface of the ion implantation chamber and the housing, and grounded to fix contaminant particles moving within the ion implantation apparatus.